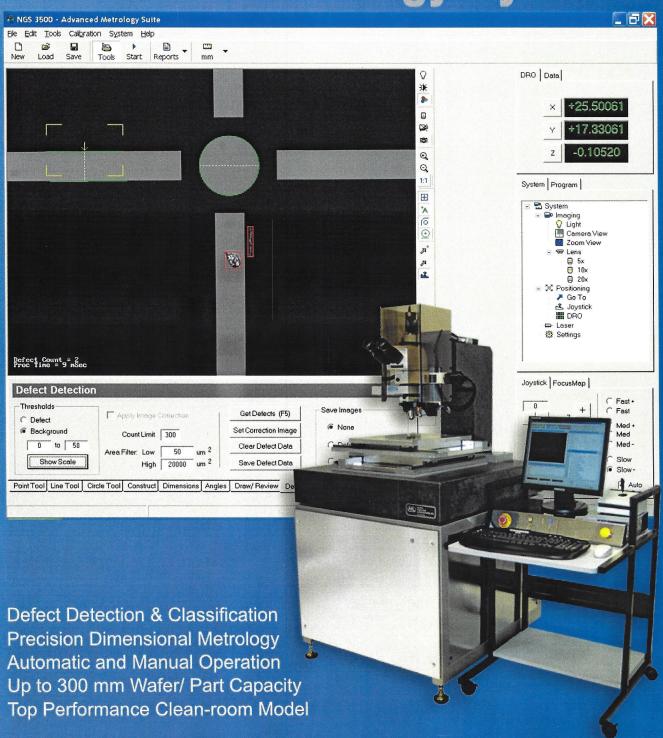
NEW

# NGS 3500L Advanced Metrology System



## NGS 3500L – Advanced Metrology System

This top performance system is designed for applications where high-speed defect detection and precision measurements on wafers and other parts are required. It is well suited for use as a dedicated production tool or as a versatile process development system. It features a powerful set of automated as well as semi-automatic optical/ video tools optimized for high accuracy, production throughput, and ease of use.

This automated and versatile platform features a standard Nikon/ Olympus bright/ dark field microscope with optional Nomarski, and precise part staging. This system offers significant and unique advantages for dual production/ engineering use, and provides the perfect solution when both defect detection and dimensional metrology are required.

The system can be configured or customized to meet your exact requirements with a variety of optical and illumination accessories, custom wafer/part fixtures, as well as custom operator interface, data formats and reports.

#### **APPLICATIONS**

- □ Wafer level defect detection & measurement
- Precision MEMS and HD component inspection
- □ Advanced microelectronics package inspection

#### **POWERFUL**

- Designed for automatic/ semi-automatic operation
- □ Extensive Defect Detection features & capability
- □ Integrated Dimensional Metrology features

#### **PRECISE**

- □ Sub-micron precision optical measurements
- High accuracy staging with 0.05 um linear encoder resolution

#### **FAST**

- 50-100 defects/ measurements per second typical per field of view
- 200mm/ second part staging speed

#### **USER FRIENDLY**

- Very easy to use, program and set up
- Highly visual data with rich color graphics & Video

#### **FLEXIBLE**

- □ Nomarski Microscope and other advanced options
- Optional Wafer and other part types handling
- Customizable for application specific solutions

## **Specifications**

### SYSTEM SPECIFICATIONS (Summary)

- 200mm (optional 300mm) wafer/ part size capacity
- ☐ Maximum stage Load capacity: 50 lb
- □ 250mm/ second maximum staging speed
- ☐ Granite base and Z-column, stainless steel finish
- □ Class 100 (10 optional) clean room compatible
- Closed loop linear stages, with position feedback from 0.05 um resolution linear glass encoders
- □ Non-linear 2D accuracy error correction
- □ Accuracy U2 (XY): 1.5+0.6L/100 um, U1 (Z): 1.5+3L/100 um. Where L is length in mm
- □ Computer: Windows XP Intel P4 system
- □ Platform: Pacific Precision Laboratories Nano 3000L
- □ Software: RMS Vision Systems' NGS 3500 Advanced Metrology Suite
- Optical System: Flat Field objectives, with optional motorized 5 position turret
- □ Camera: High resolution CCD array 60+db S/N ratio
- □ Image Processing 256 grayscale with 1:5-1:50 subpixel ratio.
- □ Video and optional Laser Auto focus
- □ Illumination: software controlled Coaxial & backlight
- Environmental: 17-23 deg C, 20-80% Humidity
- □ Electrical 120/240 VAC, 15A single phase
- □ Footprint: WxD: 32x36 inch. Height: 67 inches
- □ Weight: 1500 lb crated

#### **SOFTWARE FEATURES**

- Automatic defect detection and classification.
- Graphical Defect maps, Image Archival, offline review of defects, and reprocessing of archived images
- □ Flexible part scanning for operator convenience and throughput optimization
- □ High Precision vision based part alignment
- □ Dimensional Metrology Tools:

Video Tools: Point, Line, Circle, Arc edge detectors with built in best fit and defect removal

Constructions: Extensive geometric constructions, with distance and angle measurements (e.g. line to

line, etc.)

Origin & Skew: Unlimited reference frames

**Tolerancing:** Dimensional, Angular, Geometric True Position (MMC. LMC. RFS)

Units: Metric & inches

Coordinates: Cartesian & Polar

Step & Repeat: Repeat Loops for repeating features

and multiple parts

Reports: Data on screen, text file, or exports to Excel

SPC: Average, SD, Range, Min, Max, Cp, Cpk Graphics & CAD: Drawing import/ Export

Other: Auto Focus, Auto Lighting & Outlier Removal